

## ABSTRACT

5 The present invention provide a ceramic substrate for semiconductor manufacture and/or inspection which is conducive to decrease in  $\alpha$ -rays radiated, and change of thermal conductivity with passage of the time, and which is superior in the temperature controllability.

10 This invention is related to a ceramic substrate for apparatuses for use in semiconductor manufacture and/or inspection,

wherein the level of  $\alpha$ -rays radiated from said ceramic substrate exceeds  $0.25 \text{ c/cm}^2 \cdot \text{hr}$  and is not higher than  $50 \text{ c/cm}^2 \cdot \text{hr}$ .